Advancements in HBM Process Technology Boosting Bandwidth and Stacking Layers for the Future

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HBM Front-end Process Migration to Boost Bandwidth and Mono Die Density

- □ Increase of I/O requires more TSV numbers (front-end process), and also bumps/pad pitches (backend process).
- □ Increase of mono die density requires front-end process migration.
- □ Die size continue to become larger in HBM by around 15%, leading to higher cost per Gb.

HBM Bandwidth Roadmap

		НВМ2е	НВМ3	НВМ3е	НВМ4	НВМ4е	НВМ5	DDR5
Bandwidth pe	r Stack (GB/s)	410-461	717-819	1024-1254	2048-2560	>3072	TBD	2.4-3.2
Speed <mark>per</mark>	Pin (Gbps)	3.2-3.6	5.6-6.4	8.0-9.8	8.0-10.0	>12	TBD	4.8-6.4
I/O Bit per	Stack (bits)	1024	1024	1024	2048	2048	4096	4
Channel _I	per Stack	8	16	16	32	32	TBD	1
Bit per Cha	nnel (bits)	128	64	64	64	64	TBD	4
Mono Die	e Density	16Gb	16Gb	24Gb	24Gb	32Gb	TBD	8-32Gb
	SK hynix	1y nm	1z nm	1b nm	1b nm	1c nm	TBD	
Process Node	Samsung	1y nm	1z nm	1a nm	1c nm	1c nm	TBD	
	Micron	1z nm		1beta nm	1beta nm	1gamma nm	TBD	



HBM Backend Process Technology Shows Migration to Boost Number of Stacking Layer

- □ SK hynix maintains its leading position in production yield and product performance by developing MR-MUF process for HBM2e, which was upgraded to Advanced MR-MUF process for 12hi products with adoption of TC bonding.
- □ For 16hi, it remains uncertain if suppliers will adopt hybrid bonding process or continue using TC-NCF and MR-MUF. Flux-less TC bonding is also considered.
- \Box For HBM4/4e, with 775μm limit in total height, joint gap height of 16hi becomes around 5μm, with core die height of 20-25μm.
- □ Expansion of production scale and process complexity of HBM will boost equipment demand.

HBM Stacking Process Technology Roadmap

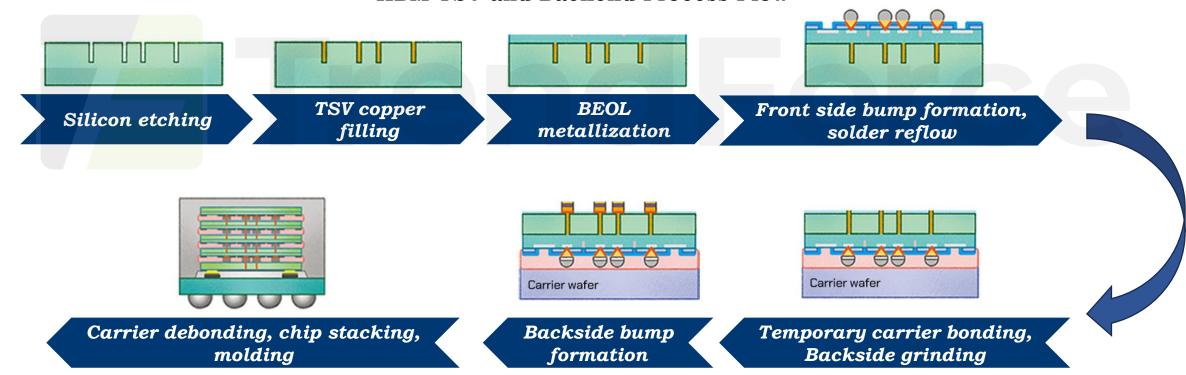
		НВМ2е		НВМ3		НВМ3е		НВМ4		НВМ4е			НВМ5			
Stacki	ing	4hi	8hi	8hi	12hi	8hi	12hi	16hi	8hi	12hi	16hi	8hi	12hi	16hi	16hi	>20hi
NVIDIA A	N GPU	Amp	ere	Нор	per		Blackwell			Rubin			Rubin Ultra	1	Ti	BD
NVIDIA Cov	VoS HBM	5		5,	/6		8			8			8/12		3D st	acking
	SK hynix	MR-N	ЛUF	MR-MUF	Adv. MR-MUF	MR-MUF	Adv. M	R-MUF	MR-MUF	Adv. M	R-MUF	MR-MUF	Adv. MR-MUF	TBD	TBD	НСВ
Stacking Technology	Samsung	TC-N	ICF	TC-I	NCF	TC-NCF N.A.		TC-NCF TBD		TC-NCF		НСВ	НСВ			
	Micron	TC-N	ICF	TC-I	NCF	TC-I	NCF	N.A.	TBD	TC-NCF	TBD		TBD		TBD	НСВ



HBM TSV and Backend Process Flow

- ☐ HBM suppliers all adopt Via-middle TSV process.
- □ Key TSV front-end process steps include silicon etching, TSV copper filling and BEOL metallization.
- □ Key TSV backend process steps include temporary carrier bonding/debonding and backside grinding.
- □ Key stacking process steps include mass reflow, thermal compression bonding and compression molding.

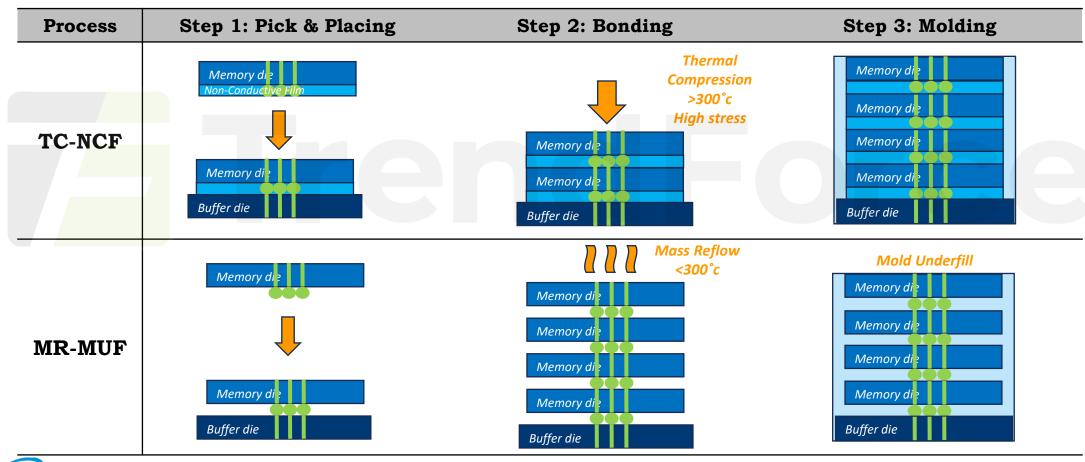
HBM TSV and Backend Process Flow





HBM Stacking Process Technology

- □ TC-NCF process adopts thermal compression with high temperature and stress when stacking each layer, leading to longer cycle time.
- □ MR-MUF process only adopts mass reflow with low temperature when completing the stacking of all layers.
- Advanced MR-MUF process adopts thermal compression with low temperature and stress when stacking each layer, and implements mass reflow when completing the stacking of all layers.



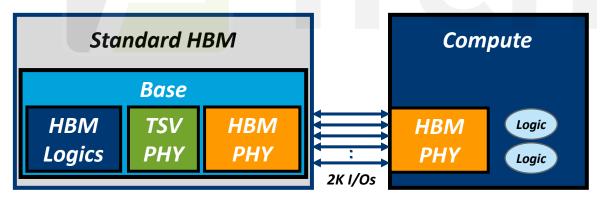


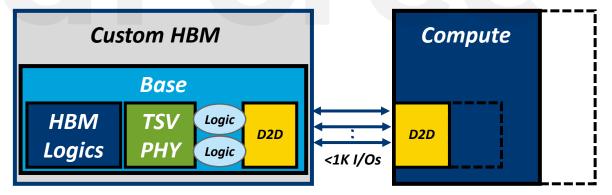
cHBM Enables Better System-level Performance and TCO

- □ In standardized HBM (sHBM) structure, HBM PHY (physical layer) blocks are put in base die and GPU/ASIC as a physical interface.
- □ Compared to sHBM, customized HBM (cHBM) offers the customization of base die, which equipped with more advanced process node.

 The logic computing functions which have higher demand for instant connection with memory can be put in base die.
- □ Better system-level performance and TCO (Total cost of ownership) can be achieved by cHBM structure by:
 - less PHY area in HBM base die, saving die size;
 - less PHY area in GPU/ASIC, saving die size, which can be used for computing functions which requires more advanced process node;
 - less data flow, IOs and channel length (from 6mm to 2mm) between HBM and GPU/ASIC are required, saving power.

Comparison Between Structure of sHBM and cHBM







HBM Base Die Manufacturing to Rely on TSMC

- With enhancing computing power, FinFET and logic process will become a MUST for HBM base die from HBM4e generation. SK hynix and Micron, without inhouse FinFET technology, become dependent on external foundry services.
- □ cHBM base die requires more integration with GPU/ASIC. TSMC, having dominated the GPU/ASIC foundry market, is the best candidate to provide foundry services for cHBM base die.
- □ HBM suppliers tend to outsource base die bumping process to base die foundries and CoWoS packaging service providers.

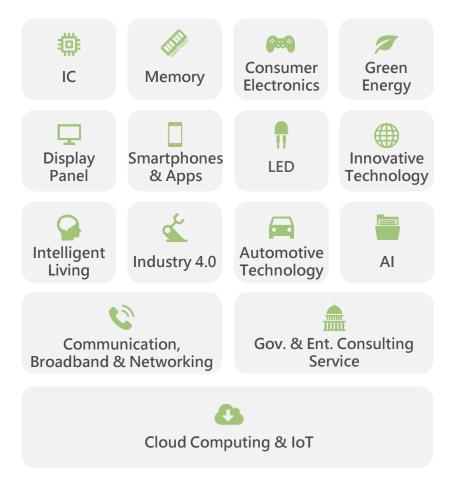
HBM Base Die Foundry Supply Overview

		SAMSUNG	SK hynix	micron.		
LIDAAA	sHBM	4nm FinFET by Samsung System LSI	12nm FinFET by TSMC	Planar by Hiroshima Fab 15		
HBM4	сНВМ	FinFET by TSMC or Samsung System LSI	N.A.	N.A.		
110044-	sHBM	FinFET by Samsung System LSI	12nm FinFET by TSMC	4nm FinFET by TSMC		
HBM4e	сНВМ	FinFET by TSMC or Samsung System LSI	3nm FinFET by TSMC	FinFET by TSMC		





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